# Monthly LabAdviser update: 1/3 2017

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| Updated Subject | Contributor | Link to the updated pages |
| **New tabletop SEM in the basement**  Equipment page. | **Pernille V. Larsen @danchip** | [SEM\_Tabletop\_1](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/SEM_Tabletop_1)  [SEM:\_Scanning\_Electron\_Microscopy](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/SEM:_Scanning_Electron_Microscopy) |
| **New ALD2 (PEALD)**  Equipment page | **Pernille V. Larsen @danchip** | [Thin\_film\_deposition/ALD2\_(PEALD)](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD2_(PEALD)) |
| **Fume Hoods**  Overview page of the Fume Hoods | **Majken Becker @danchip** | [Overview\_of\_Fume\_Hoods](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Overview_of_Fume_Hoods) |
| **Wet silicon nitride etch**  Updated comparison page  New wet bench for nitride etch | **Majken Becker @danchip** | [Etch/Etching\_of\_Silicon\_Nitride](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Etching_of_Silicon_Nitride)  [Etch/Wet\_Silicon\_Nitride\_Etch](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Wet_Silicon_Nitride_Etch) |
| **Wet silicon oxide etch (BHF)**  Corrected so it fits the wet benches | **Majken Becker @danchip** | [Etch/Wet\_Silicon\_Oxide\_Etch\_(BHF)](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/Wet_Silicon_Oxide_Etch_(BHF)) |
| **Wet silicon etch (KOH)**  Updated comparison page  New wet bench and Fume hood. | **Majken Becker @danchip** | [Etch/Etching\_of\_Silicon](http://labadviser.danchip.dtu.dk/index.php?title=Specific_Process_Knowledge/Etch/Etching_of_Silicon)  [Etch/KOH\_Etch](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/KOH_Etch) |
| **PECVD4**  PECVD equipment page has been updated  Pre-release tests has been done | **Berit Herstrøm @danchip** | [PECVD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/PECVD)  [PECVD/Pre-release\_tests\_on\_PECVD4](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/PECVD/Pre-release_tests_on_PECVD4) |
| **Lift-off**  New bench for lift-off | **Rune K. Christiansen @danchip** | [Lithography/LiftOff](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/LiftOff) |
| **Resist strip**  New wet bench for resist strip | **Rune K. Christiansen @danchip** | [Lithography/Strip#Resist\_Strip](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/Strip#Resist_Strip) |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

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| **Manual for Picosun ALD 2** |
| **Manual for PECVD4** |
| **Manual for Sputter Coater 04** |
| **Manual for Nitride etch: H3PO4** |
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| **Manual for HF and BHF in various dedicated baths** |
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| **Manual for 'Si Etch 1: KOH' and 'Si Etch 2: KOH'** |
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| **Manual for Wafer Cleaning** |
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| **Manual for Mask Cleaning** |
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| **Manual for Piranha** |
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| **Manual for RTP Jipelec** |
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| **Manual for Wafer Bonder 2** |
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| **Manual for Polymer Injection Molding** |
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| **Manual for Optical Profiler (Sensofar)** |
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| **Manual for Four point probe** |
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